

Subst. Form PTO-1449

Docket Number (Optional)

SAM-0313CIP

Application Number

10/625,007

INFORMATION DISCLOSURE CITATION
IN AN APPLICATION

Applicant

Kyoung-woo Lee, et al.

Filing Date

July 23, 2003

Group Art Unit

1326

(Use several sheets if necessary)

U. S. Patent Documents

EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
lm	AA	6,559,520	5/6/03	Matsuki, et al. ✓	257	642	4/25/02
	AB	6,514,880	2/4/03	Matsuki, et al. ✓	438	780	4/6/01
	AC	6,455,445	9/24/02	Matsuki ✓	438	789	3/28/01
	AD	6,432,846	8/13/02	Matsuki ✓	438	790	10/18/00
	AE	6,410,463	6/25/02	Matsuki ✓	438	790	10/18/00
	AF	6,383,955	5/7/02	Matsuki ✓	438	790	6/7/99
	AG	6,352,945	3/5/02	Matsuki, et al. ✓	438	778	6/7/99
	AH	6,057,239	5/2/00	Wang, et al. ✓	438	689	12/17/97
	AI	5,989,997	11/23/99	Lin, et al. ✓	438	622	4/17/98
	AJ	2001/0046778	11/29/01	Wang, et al. ✓	438	706	3/22/00
	AK	6,465,358	10/15/02	Nashner, et al.	438	700	10/6/00

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
lm	AL	KR 0029195	25-5-00	Korea	Co9K	3/10		X
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

lm	AR	Jiang, P, et al., Trench Etch Processes for Dual Damascene Patterning of Low-k Dielectrics, J. Vac. Sci. Technol. A 19(4), Jul/Aug. 2001, pgs. 1388-1391.
	AS	
	AT	

EXAMINER

lm

DATE CONSIDERED

05-25-05

EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609; Draw line through citation if not in conformance and not considered. Include copy with next communication to applicant.

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lm	BA	6,391,761	5/21/02	Lui ✓	438	618	9/20/99
	BB	6,323,121	11/27/01	Liu, et al. ✓	438	633	5/12/00
	BC	6,319,815	11/20/01	Iguchi, et al. ✓	438	624	10/18/99
	BD	6,221,759	4/24/01	Bothra, et al. ✓	438	627	6/19/98
	BE	6,093,966	7/25/00	Venkatraman, et al. ✓	257	751	3/20/98
	BF						
	BG						
	BH						
	BI						
	BJ						
	BK						

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
							YES	NO
	BL							
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	BN							
	BO							
	BP							
	BQ							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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	BT	

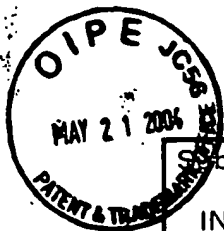
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Sheet 1 of 2

Subst. Form PTO-1449

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Application Number

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Kyoung-woo Lee, et al.

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Group Art Unit

1765

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U. S. Patent Documents

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	AA						
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	AK						

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	AL							
	AM							
	AN							
	AO							
	AP							
	AQ							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

	AR	
lm	AS	S. Wolf and R.N. Tauber, Silicon Processing, Lattice Press, Vol. 1, Page 171
	AT	

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Subst. Form PTO-1449 INFORMATION DISCLOSURE CITATION IN AN APPLICATION <i>(Use several sheets if necessary)</i>				Docket Number (Optional) SAM-0313CIP		Application Number 10/625,007	
				Applicant Kyoung-woo Lee, et al.			
				Filing Date July 23, 2003		Group Art Unit 1765	

U. S. Patent Documents							
EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
	BA						
	BB						
	BC						
	BD						
	BE						
h	BF	6,458,705	10/01/02	Hung, et al.	438	692	06/06/01
↓	BG	6,461,955	10/08/02	Tsu, et al.	438	618	03/09/00
↓	BH	6,509,267	01/21/03	Woo, et al.	438	687	06/20/01
↓	BI	2002/0009873	01/24/02	Usami	438	620	07/23/01
	BJ						
	BK						

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						YES	NO	
	BL							
	BM							
	BN							
	BO							
	BP							
	BQ							

OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)		
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EXAMINER <i>hmg</i>	DATE CONSIDERED <i>05-25-05</i>
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Kyoung-woo Lee, *et al.*

Filing Date

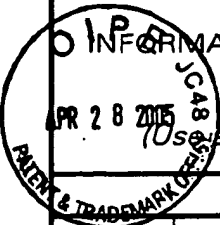
07/23/03

Group Art Unit

1765

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

APR 28 2005
 (Use several sheets if necessary)



U. S. Patent Documents

EXAMINER INITIALS	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	AA					
	AB					
	AC					
	AD					
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	AJ					
	AK					

FOREIGN PATENT DOCUMENTS

		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation	
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	AL							
	AM							
lm	AN	2000-340649	12/08/00	Japan	H01L	21/768		X
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OTHER DOCUMENTS (Including Author, Title, Date, Pertinent Pages, Etc.)

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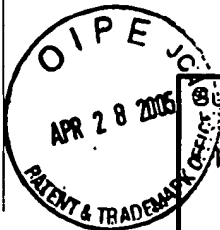
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Group Art Unit

1765

U. S. Patent Documents

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	BA						
	BB						
	BC						
	BD						
	BE						
	BF						
	BG						
	BH						
	BI						
hn	BJ	6,127,089	10/03/00	Subramanian, <i>et al.</i>	430	270	08/28/98
	BK						

FOREIGN PATENT DOCUMENTS

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							YES	NO
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Sheet 1 of 1

5-26-5

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INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)		Applicant Kyoung-woo Lee, et al.						
		Filing Date July 23, 2003		Group Art Unit 1326				
U. S. Patent Documents								
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
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	AJ							
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FOREIGN PATENT DOCUMENTS								
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	Translation YES NO	
	AL							
lh	AM	10-0364053	26-11-02	Korea	H01L	21/31		X
	AN							
	AO							
	AP							
	AQ							
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	AT							
EXAMINER lh				DATE CONSIDERED 05-25-05				
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